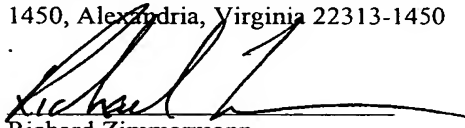


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Seong Hwan Park et al.	)	I hereby certify that this paper and the
	)	documents referred to as enclosed
Serial No.: To be assigned	)	therewith are being deposited with the
	)	United States Postal Service as Express
Filed: November 26, 2003 (Herewith)	)	Mail, Airbill No. EV323777167US
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Semiconductor Device	)	Commissioner for Patents, P.O. Box
	)	1450, Alexandria, Virginia 22313-1450
Group Art Unit: To be assigned	)	
	)	
Examiner: To be assigned	)	Richard Zimmermann
	)	
	)	
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INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
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Sir:

Submitted herewith for consideration by the examiner is a copy of the document identified on the attached Form PTO-1449. Entry and consideration of the submitted document is solicited.


The Commissioner is authorized to charge any fee deficiency required by this paper, or credit any overpayment, to Deposit Account No. 13-2855.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP  
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November 26, 2003

By:

  
Michael R. Hull  
Reg. No. 35,902

Form PTO-1449 (Modified) U.S. Department of Commerce Patent and Trademark Office  <b>INFORMATION DISCLOSURE STATEMENT</b>	Atty. Docket No. <b>30205/39511</b>	Serial No. <b>To be Assigned</b>
	Applicant <b>Seong Hwan Park</b>	
	Filing Date <b>November 26, 2003</b>	Group <b>To be Assigned</b>

U.S. PATENT DOCUMENTS							
*Examiner Initials		Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate

FOREIGN PATENT DOCUMENTS								
*Examiner Initials		Document Number	Publication Date	Country	Class	Subclass	Translation	
							Yes	No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
		Fujimura et al., "Ashing of the Ion Implanted Resist Layer," Digest of Papers 1989 2 <sup>nd</sup> MicroProcess Conference, July 2-5, 1989.

EXAMINER	DATE CONSIDERED
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance <u>and</u> not considered. Include copy of this form with next communication to applicant.	